

Amendments to the Claims:

Please amend claims 1, 2, and 10 as follows. Following is a complete listing of the claims pending in the application, as amended:

1. (Currently amended) A reactor for electrochemically processing a microelectronic workpiece, comprising:

a movable electrode assembly disposed for movement along a motion path, the motion path including at least a portion thereof over which the electrode assembly is positioned for processing a microelectronic workpiece, the movable electrode assembly including an electrode spaced apart from the microelectronic workpiece during processing; and

a cleaning electrode located along the motion path of a movable electrode assembly, with the movable electrode assembly being movable toward and away from the cleaning electrode.

2. (Currently amended) The reactor of claim 1 and further comprising a programmable controller connected to ~~control~~ direct the movable electrode assembly ~~into~~ to move to the cleaning electrode during a cleaning cycle.

3. (Original) The reactor of claim 2 wherein the programmable controller connects the movable electrode assembly as an anode and the cleaning electrode as a cathode during the cleaning cycle.

4. (Original) The reactor of claim 2 wherein the cleaning electrode is disposed along a position of the motion path that is beyond the range of motion required to process a microelectronic workpiece.

5. (Original) The reactor of claim 4 wherein the programmable controller is programmed to conduct a cleaning cycle while a microelectronic workpiece is disposed in the reactor for processing.

6. (Original) The reactor of claim 4 wherein the programmable controller is programmed to execute a cleaning cycle during a workpiece processing cycle in which a microelectronic workpiece is under process.

7. (Original) The reactor of claim 1 wherein the cleaning electrode comprises platinized titanium.

8. (Original) The reactor of claim 1 wherein the movable electrode assembly comprises one or more sets of fluid delivery ports that deliver a fluid to the surface of the microelectronic workpiece.

9. (Original) The reactor of claim 8 wherein said fluid is a rinse solution.

10. (Currently amended) The reactor of claim 8 wherein said fluid is an electrolyte.

11. (Original) The reactor of claim 8 wherein said movable electrode assembly further includes one or more sets of fluid recovery ports.

12. (Original) The reactor of claim 1 wherein said movable electrode assembly further includes one or more sets of fluid delivery ports, and one or more sets of fluid recovery ports.

13-25. (Cancelled)